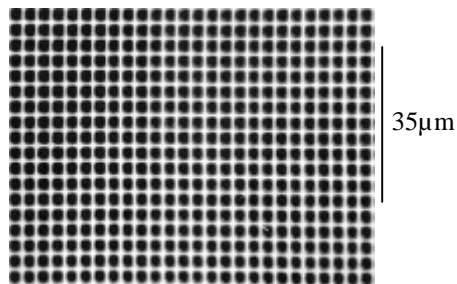
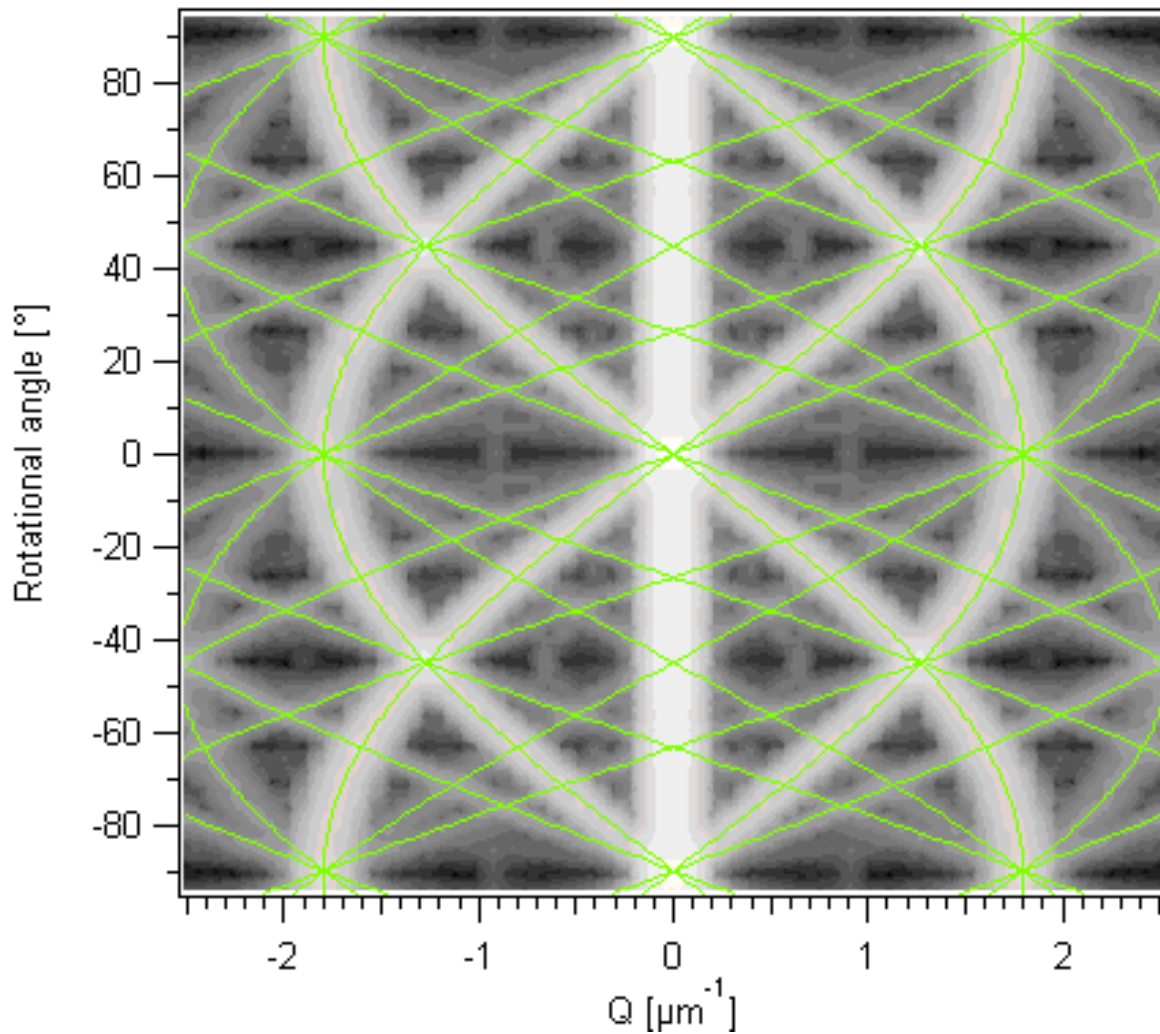


USANS scattering patterns of a silicon macropore array

TEM-Picture of the silicon macropore array



pore diameter : $\sim 2 \mu\text{m}$
pore depth : $\sim 100 \mu\text{m}$
lattice distance : $\sim 3.5 \mu\text{m}$



The scattering patterns have been recorded by stepwise rotation of the silicon macropore array in relation to the resolution axes of the USANS Instrument S18.